भारतीय मानक Indian Standard

IS 5920 (Part 9) : 2024 ISO 10110-14 : 2018

प्रकाशिकी और फोटोनिक्स — प्रकाशीय तत्वों और प्रणालियों के लिए आरेखण तैयार करना

भाग 9 वेवफ्रंट विरूपण सहनशीलता

# Optics and Photonics — Preparation of Drawings for Optical Elements and Systems

**Part 9 Wavefront Deformation Tolerance** 

ICS 37.020; 01.100.20

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भारतीय मानक ब्यूरो BUREAU OF INDIAN STANDARDS मानक भवन, 9 बहादुर शाह ज़फर मार्ग, नई दिल्ली - 110002 MANAK BHAVAN, 9 BAHADUR SHAH ZAFAR MARG NEW DELHI - 110002 www.bis.gov.in www.standardsbis.in

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#### NATIONAL FOREWORD

This Indian Standard (Part 9) which is identical to ISO 10110-14 : 2018 'Optics and photonics — Preparation of drawings for optical elements and systems — Part 14: Wavefront deformation tolerance' issued by the International Organization for Standardization (ISO) was adopted by the Bureau of Indian Standards on the recommendation of the Optics and Photonics Sectional Committee and after approval of the Production and General Engineering Division Council.

This standard specifies rules for the indication of the permissible deformation of a wavefront transmitted through or, in the case of reflective optics, reflected from an optical element or assembly in the ISO 10110 series, which standardizes drawing indications for optical elements and systems.

IS 5920 (Part 1) supersedes the originally published Indian Standard IS 5920 : 1970 'Recommendation for the preparation of drawing for optical elements and system'.

This standard has been published in thirteen parts. The other parts in this series are:

- Part 1 General
- Part 2 Surface form tolerances
- Part 3 Centering tolerances
- Part 4 Surface imperfections
- Part 5 Surface texture
- Part 6 Surface treatment and coating
- Part 7 Non-tolerance data
- Part 8 Aspheric surfaces
- Part 10 Diffractive surfaces
- Part 11 Laser irradiation damage threshold
- Part 12 Stress birefringence, bubbles and inclusions, homogeneity, and striae
- Part 13 General description of surfaces and components

The text of ISO standard has been approved as suitable for publication as an Indian Standard without deviations. Certain conventions are, however, not identical to those used in Indian Standards. Attention is particularly drawn to the following:

- a) Wherever the words 'International Standard' appear referring to this standard, they should be read as 'Indian Standard'; and
- b) Comma (,) has been used as a decimal marker while in Indian Standards, the current-practice is to use a point (.) as the decimal marker.

In this adopted standard, reference appears to certain International Standard for which Indian Standards also exists. The corresponding Indian Standard, which is to be substituted in its respective place, is given below along with its degree of equivalence for the edition indicated:

International Standard	Corresponding Indian Standard	Degree of Equivalence	
ISO 10110-1 Optics and photonics — Preparation of drawings for optical elements and systems — Part 1: General	IS 5920 (Part 1) : 2024/ ISO 10110-1 : 2019 Optics and photonics — Preparation of drawings for optical elements and systems: Part 1 General ( <i>first</i> <i>revision</i> )	Identical	

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# Introduction

This document makes it possible to specify a functional tolerance for the performance (expressed as single-pass wavefront deformation) of an optical system, which may have optical power or contain powered optical elements. This tolerance therefore includes the effect of surface form deformations, inhomogeneities, and possible interactions among the various individual errors.

Optical elements are often tested in a "double-pass" configuration, in which the wavefront passes through or, in the case of reflective optics, reflects from the element under test twice, as shown in ISO/TR 14999-1:2005, Figure 18.

# Indian Standard

# OPTICS AND PHOTONICS — PREPARATION OF DRAWINGS FOR OPTICAL ELEMENTS AND SYSTEMS PART 9 WAVEFRONT DEFORMATION TOLERANCE

# 1 Scope

This document specifies rules for the indication of the permissible deformation of a wavefront transmitted through or, in the case of reflective optics, reflected from an optical element or assembly in the ISO 10110 series, which standardizes drawing indications for optical elements and systems.

This document is also applicable when using optical systems with general surfaces (ISO 10110-19).

The deformation of the wavefront refers to its departure from the desired shape. The tilt of the wavefront with respect to a given reference surface is excluded from this document.

There is no requirement that a tolerance for wavefront deformation is indicated.

#### 2 Normative references

The following documents are referred to in the text in such a way that some or all of their content constitutes requirements of this document. For dated references, only the edition cited applies. For undated references, the latest edition of the referenced document (including any amendments) applies.

ISO 10110-1, Optics and photonics — Preparation of drawings for optical elements and systems — Part 1: General

ISO 14999-4, Optics and photonics — Interferometric measurement of optical elements and optical systems — Part 4: Interpretation and evaluation of tolerances specified in ISO 10110

## 3 Terms and definitions

For the purposes of this document, the terms and definitions given in ISO 14999-4 apply.

ISO and IEC maintain terminological databases for use in standardization at the following addresses:

- ISO Online browsing platform: available at https://www.iso.org/obp
- IEC Electropedia: available at <a href="http://www.electropedia.org/">http://www.electropedia.org/</a>

NOTE ISO 14999-4 provides the definitions for all the deformation functions.

## 4 Specification of tolerances for wavefront deformation

#### 4.1 General

It should be noted that it is possible to specify a tolerance on the wavefront deformation only - without specifying tolerances on the individual surfaces. In this case, the manufacturer has to ensure that the wavefront satisfies the specified tolerance. However, the manufacturer is not bound by tolerances on the form of the individual surfaces of the element or system. The manufacturer is free, for instance, to allow the surface form deformations to be large provided they cancel each other.

It is also possible to supply a tolerance for the wavefront deformation, according to this document, in addition to tolerances on the form of the individual surfaces and/or inhomogeneity (according to ISO 10110-5 and ISO 10110-18, respectively). In this case, the manufacturer has to ensure that all of the individual tolerances (surface form tolerances and material imperfections) are upheld, as well as ensuring that the wavefront is of the specified quality.

In the case of double-pass testing, the additional wavefront deformation caused by the second transmission through the element has to be accounted for when comparing the measurement results with the specified tolerances. If the wavefront is not severely deformed by passing once through the element under test, and reflects from a high quality mirror, so that it returns through the identical portion of the test element to the interferometer, then the observed deformation of the wavefront is twice the (single-pass) wavefront deformation (defined in ISO 14999-4). That is, the wavefront deformation is one-half the observed wavefront deformation.

If the wavefront is severely deformed by the element under test, then the individual rays do not pass through the same positions in the element under test on their return path, and the wavefront deformation is not exactly twice that of the single path case.

The given wavefront deformation is only valid at the specified wavelength.

The tolerances for wavefront deformation are indicated by specifying the maximum permissible values of the power deviation, irregularity, and/or rotationally invariant irregularity. In addition, tolerances for three root-mean-square measures of wavefront deformation (rms total, rms irregularity and rms rotationally varying irregularity) may be specified. See ISO 14999-4 for definitions.

NOTE 1 The power deviation is meaningful only when the location of the image is specified. If the location of the image is unspecified, the power deviation is defined to be zero.

NOTE 2 Methods for determining the amount of power deviation, irregularity and rotationally invariant irregularity of a wavefront are given in ISO 14999-4.

It is not necessary that tolerances be specified for all types of wavefront deformation.

There is no requirement that a tolerance for wavefront deformation be indicated. If such a tolerance is specified, it does not take precedence over a surface form tolerance according to ISO 10110-5. If tolerances for both the surface form and the wavefront deformation are given, they are both to be upheld.

## 4.2 Units

The maximum permissible values for power deviation, irregularity, rotationally invariant irregularity and, if applicable, any target aberrations should be specified in units of nanometres. If wavelengths are to be used, the wavelength shall also be indicated on the drawing.

NOTE 1 These quantities are defined with reference to a wavefront passing once through the element or system under test (single-pass).

If a specification is to be given for one or more rms wavefront deformation types, the specification shall also be in units of nanometres or wavelengths (single-pass, see NOTE 1).

NOTE 2 One "wave" is 1 × the wavelength (in nanometres) in which the wavefront deformation is specified.

NOTE 3 The specification of a tolerance for an rms deformation type requires that the optical system be analysed digitally.

The terminology of interferometry employing the unit "waves" is widely used for the specification of tolerances. However, the usage of non-interferometric methods for testing of optical parts has recently become more important. Therefore, unlike in the earlier versions of this document, "nanometres" is now the preferred standard unit to express wavefront deviations. The use of waves is still permitted given that the reference wavelength is explicitly stated.

## 4.3 Wavelength

If wave units are to be used, the wavelength shall also be indicated on the drawing in order to reduce confusion. If different wavelengths are used for measuring, separately calculated wavefront deformations are needed and can be provided as alternatives.

# 4.4 Target aberrations

Frequently, the nominal theoretical wavefront is spherical or planar. In some cases, to allow for the presence of small amounts of residual aberration in the design of an optical system, non-zero target values may be specified for polynomial aberration types.

# 5 Indication in drawings

## 5.1 General

The location of the stop surface or pupil shall be indicated according to ISO 10110-1. See Figure 2.

The tolerance for wavefront deformation shall be indicated at the optical axis by a code number and the tolerances for power deviation, irregularity, rotationally invariant irregularity and rms deformation types shall be indicated as appropriate (see <u>5.2</u>).

Wavefront deformation should be specified in nanometres. However if wave units are to be used, the wavelength shall also be indicated. All quantities shall have their units specified. If no unit is indicated then wavelength units are implied.

No provision is given for the specification of a PV-tolerance for the total wavefront deformation (that is, including both the power deviation and the irregularity). If such a specification is necessary, this information shall be given in a note on the drawing, for example: "Total wavefront deformation shall not exceed 150 nm" or "Total wavefront deformation shall not exceed 0,25 waves".

NOTE Such a specification might, for example, be useful for optical elements to be used in interferometers.

See <u>Clause 6</u> for examples of tolerance indications.

## 5.2 Code number

#### 5.2.1 Basic forms

The indication shall consist of one basic form and may be supplemented by additional forms. Multiple forms shall be separated by a semicolon. The code number for wavefront deformation is 13/.

 $13/A(B/C); \lambda = E$ 

or

13/A(B/C) RMSx < D;  $\lambda = E$ 

(where *x* is one of the letters t, i or a; see ISO 14999-4).

or

 $13/RMSx < D; \lambda = E$ 

(where *x* is one of the letters t, i or a; see ISO 14999-4).

NOTE 1 In former editions 13/— RMSx < D;  $\lambda = E$  was used.

or

#### 13/AX; AY (B/CX; CY)

The quantity *A* is either:

- a) the maximum permissible (single-pass peak-to valley value) power deviation  $PV(f_{WS})$  as defined in ISO 14999-4 expressed in nanometres, micrometres, or waves, or
- b) a dash (—) indicating that no explicit tolerance for power deviation is given.

The quantities AX, AY are either

- a) the maximum permissible power deviation (single pass peak-to-valley value)  $PV(f_{WC,x})$  and  $PV(f_{WC,y})$  for cylindric and similar wavefront deformation defined in ISO 14999-4, expressed in nanometers, micrometers, or waves, or
- b) a dash (—) indicating that no explicit tolerance for power deviation is given.

The quantity *B* is either:

- a) the maximum permissible value (single-pass peak-to-valley value)  $PV(f_{WI})$  of irregularity,
- b) the maximum permissible value (single pass peak-to-valley value)  $PV(f_{WI,CY})$  of irregularity for cylindric and similar wavefront deformation as defined in ISO 14999-4, expressed in nanometers, micrometers, or waves when *AX* and/or *AY* are used, or
- c) a dash (—) indicating that no explicit tolerance for irregularity is given.

The quantity *C* is:

- a) the maximum permissible value of the (single-pass peak-to valley value)  $PV(f_{WRI})$  of rotationally invariant irregularity. If no tolerance is given, the slash (/) is replaced by the final parenthesis, i.e. 13/A(B), or
- b) a dash (—) indicating that no explicit rotationally invariant irregularity tolerance is given.

The quantities *CX* and *CY* are

- a) the maximum permissible value (peak-to-valley)  $PV(f_{WTI,x})$ ,  $PV(f_{WTI,y})$  of translationally invariant irregularity for cylindric and similar wavefront deformation, expressed in nanometres, micrometers or waves, as defined in ISO 14999-4. *CX* and *CY* are used for the symmetry specification across the x and y axis; or
- b) a dash (—) indicating that no explicit translationally invariant irregularity tolerance for both or one of them is given.

If no tolerance is given, the slash (/) is replaced by the closing parenthesis, i.e. 13/AX; AY(B).

The quantity *D* is the maximum permissible value of the rms-quantity of the type specified by *x*, where *x* is one of the letters t, i or a. These deviations are defined

- a) for rotationally symmetric wavefront deformation rms ( $f_{WD}$ ) the rms total for t, rms ( $f_{WI}$ ) the rms irregularity for i and rms ( $f_{WRV}$ ) the rms rotationally varying (asymmetric) irregularity for a as defined in ISO 14999-4 or
- b) for cylindric and similar wavefront deformation in rms ( $f_{WD,CY}$ ) the rms total for t, rms ( $f_{WI,CY}$ ) the rms irregularity for i and rms ( $f_{WTV}$ ) the rms translationally varying (asymmetric) irregularity for a as defined in ISO 14999-4.

The specification of more than one type of rms-deviation is allowed. These specifications shall be separated by a semicolon, as shown in <u>Clause 6</u>, Examples 7a and 7b.

The quantity *E* is the wavelength in which the wavefront deformation is specified.

NOTE 2 The values *A* and *C* are best used for types of rotationally invariant or similar wavefront deformations. The values *AX*, *AY* as well as *CX* and *CY* are best used for types of cylindric, toric or similar wavefront deformations.

If no tolerance is given for any of the deformation types, then *A*, *B*, *C*, RMS*x*<D the divisor line (/) and the parenthesis are replaced by a single dash (—), i.e. 13/—.



# Figure 1 — Example of an indication of a tolerance for wavefront deformation, with planar illumination



Figure 2 — Example of an indication of a tolerance for wavefront deformation, with planar illumination

#### 5.2.2 Additional forms

#### 5.2.2.1 PV and robust PV wavefront deviation

PV(F)

and

PVr(G)

The quantity *F* is the maximum permissible peak-to-valley value of the total wavefront deviation  $PV(f_{WD})$  as defined in ISO 14999-4, expressed in nanometres, micrometres, or waves.

The quantity *G* is the maximum permissible robust peak-to-valley value of the total wavefront deviation  $PVr(f_{WD})$  as defined in ISO 14999-4, expressed in nanometres, micrometres, or waves.

PV and PVr values are taking a radius correction into account. Thus, an applicable radius correction reduces the peak-to-valley and robust peak-to-valley values rather than a power deviation which does not reduce the values.

Due to the usage of Zernike polynomials, PVr is only applicable for circular apertures.

See <u>Clause 6</u>, Examples 8 and 9.

#### 5.2.2.2 Wavefront deviation described by Zernike coefficients

Z(n, m) (PV < H; RMS < K)

where (n, m) are indices for one or a set of tuples which reflect a degree of Zernike polynomials.

The quantity H is the maximum permissible peak-to-valley value of the wavefront deviation that is described by one or the combined function of a set of Zernike polynomials as defined in ISO 14999-4 where (n, m) are indices for one or a set of Zernike polynomial(s) according to ISO 14999-4.

The quantity *K* is the maximum permissible rms value of the wavefront deviation that is described by one or the combined function of a set of Zernike polynomials as defined in ISO 14999-4, where (n, m) are indices for one or a set of Zernike polynomial(s) according to ISO 14999-4.

A set of Zernike polynomials Z(n1, m1), Z(n2, m2), Z(n3, m3), or Z(N = x) is interpreted as the sum function of these Zernike polynomials.

Peak-to-valley and rms wavefront deviations described by Zernike coefficients take the radius correction into account. Thus, an applicable radius correction reduces the peak-to-valley and rms values rather than a power deviation which does not.

Both peak-to-valley as well as rms Zernike specifications are only applicable for circular apertures.

See <u>Clause 6</u>, Examples 10 and 11.

#### 5.3 Area

The indicated wavefront tolerance applies to the complete optically effective area if no constraints are given.

If the indication is to be applied to a smaller test field within a larger test region, as defined in ISO 10110-1, then the test field dimension shall be appended to the tolerance.

13/A(B/C) RMSx < D (all  $\emptyset$ ...)

See <u>Clause 6</u>, Example 4a.

A test field in any shape (e.g. rectangular) can be defined and shown in any position within the test region as a dimensioned area. Appropriate requirements indicated by a leader line connecting a "13/" specification to this test field shall apply to all possible positions of the test field within the test region. In this case, the geometric shape of the test field shall be appended to the appropriate tolerance indication as follows.

13/A(B/C) RMSx < D (all ... × ...)

See <u>Clause 6</u>, Example 4b.

#### 5.4 Location

The indication shall be entered near the optical element to which it refers. If necessary, the indication may be connected to the optical axis by a leader, as shown in <u>Figures 1</u> and <u>2</u>.

In cases where the optical axis is not normal to the surfaces of the element, it may be necessary to indicate the test region for wavefront deformation in a cross-section perpendicular to the optical axis. In this case the indication of wavefront deformation shall be associated with the test region (see Figures 3 and 4).

For elements requiring indications for wavefront deformation along multiple test paths, the various test paths shall be indicated with reference letters, as shown in Figure 5. The indications for wavefront deformation are to be associated with the letters of the input and output test paths, as shown in Figure 5.



Figure 3 — Indication of the wavefront quality specification referencing an indicated test region



Figure 4 — Indication of the wavefront quality specification referencing an indicated test region



#### Кеу

CE: 13/3(1);  $\lambda = 546,07$  nm CF: 13/1(0,2);  $\lambda = 546,07$  nm DE: 13/3(1);  $\lambda = 546,07$  nm DF: 13/1(0,2);  $\lambda = 546,07$  nm

# Figure 5 — Indication of the wavefront quality specification for an element having multiple test paths

NOTE The tolerance for the single-pass ray paths from C to E and from D to E is 3 waves for power deviation and 1 wave for irregularity. The tolerance for the single-pass ray paths from C to F and from D to F is 1 wave for power deviation and 0,2 waves for irregularity. The wavelength for all wavefront deformation specifications is  $\lambda = 546,07$  nm.

#### 5.5 Indication of the object point location

For diverging or converging illumination, the position of the object point shall be indicated on the drawing. See <u>Figure 6</u>.

The absence of an indication of the position of the object point implies collimated (planar wavefront) illumination, as shown in Figures 1, 2, 3, 4 and 5.



Figure 6 — Example showing the indication of the object point on the drawing

#### 5.6 Specification of the image point location

Optionally, the location of the image point may be given with a dimensional tolerance. If the image location is given, it shall be distinguished from the object location by the letters "im" associated with the indicated position. See Figure 7.

NOTE The power deviation, which is a measure of the extent to which this tolerance is upheld, is not meaningful unless the image position is indicated. If no restrictions are specified on the location of the image of the optical system under test, the reference sphere is identical to the approximating spherical wavefront, and the power deviation is defined to be zero.



Figure 7 — Example showing the indication of the image position

## 5.7 Indication of target aberrations

Target values for one or more of the polynomial aberrations defined in Annex A of ISO/TR 14999-2:2005 may be specified following the word "Target". The form for the indication of a target aberration is as follows:

 $C_i = V$ 

where

- *i* is the identifying index of the desired polynomial term;
- *V* is the numerical value of the target.

See <u>Clause 6</u>, Example 12.

# 6 Examples of tolerance indications

The following examples are designed to illustrate the indications in drawings in accordance with this document.

EXAMPLE 1 13/600 nm (300 nm/150 nm);  $\lambda$  = 546,07 nm

The tolerance for the power deviation is 600 nm of single-pass wavefront deformation. The total irregularity shall not exceed 300 nm. The rotationally invariant irregularity shall be less than 150 nm of single-pass wavefront deformation. The wavelength for all wavefront deformation specifications is  $\lambda = 546,07$  nm.

EXAMPLE 2  $13/-(1); \lambda = 632,8 \text{ nm}$ 

The irregularity shall not exceed 1 wave (at  $\lambda$  = 632,8 nm) of single-pass wavefront deformation. No tolerance for power deviation is given.

#### EXAMPLE 3 13/5 (—) RMSi < 0,05; $\lambda$ = 632,8 nm

The tolerance for the power deviation (in addition to the amount corresponding to the dimensional tolerance given in the indication of the image position) is 5 waves of single-pass wavefront deformation. No specific tolerance is given for irregularity or rotationally invariant irregularity, but the rms value of the irregularity shall be less than 0,05 waves of single-pass wavefront deformation. The wavelength for all wavefront deformation specifications is  $\lambda = 632,8$  nm.

EXAMPLE 4a 13/3 (1/0,5) (all  $\emptyset$  30);  $\lambda$  = 546,07 nm

The wavefront deformation tolerances apply to all possible locations of a 30 mm diameter test field within the specified test region. The tolerance for the power deviation is 3 waves of single-pass wavefront deformation. The total irregularity shall not exceed 1 wave of single-pass wavefront deformation. The rotationally invariant irregularity shall be less than 0,5 waves of single-pass wavefront deformation. The wavelength for all wavefront deformation specifications is  $\lambda = 546,07$  nm.

EXAMPLE 4b 13/0,5 (—) RMSi < 0,05 (all  $10 \times 10$ );  $\lambda = 546,07$  nm

For all possible positions of a 10 × 10 rectangular test field within the specified test region of the element, the (single-pass) power deviation shall not exceed 0,5 waves, and the rms irregularity shall be less than 0,05 waves in single-pass wavefront deformation. The wavelength for all wavefront deformation specifications is  $\lambda = 546,07$  nm.

#### EXAMPLE 5 13/3 (1); $\lambda$ = 632,8 nm

The tolerance for the power deviation is 3 waves in single-pass; the total irregularity shall not exceed 1 wave of single-pass wavefront deformation. The wavelength for all wavefront deformation specifications is  $\lambda = 632,8$  nm.

EXAMPLE 6 13/— RMSt < 0,07;  $\lambda$  = 546,07 nm

No specific tolerance for the power deviation, irregularity, or rotationally invariant irregularity is given; however, the total rms difference between the actual wavefront and the theoretical wavefront shall be less than 0,07 waves of single-pass wavefront deformation. The wavelength for the wavefront deformation specifications is  $\lambda = 546,07$  nm.

EXAMPLE 7a 13/— RMSi < 0,07; RMSa < 0,03; λ = 632,8 nm

No specific tolerance for the power deviation, irregularity, or rotationally invariant irregularity is given; however, the rms irregularity shall be less than 0,07 waves of single-pass wavefront deformation, and the rms rotationally varying wavefront deviation shall be less than 0,03 waves of single-pass wavefront deformation. The wavelength for all wavefront deformation specifications is  $\lambda = 632,8$  nm.

EXAMPLE 7b 13/— RMSt < 0,07; RMSi < 0,04 ;  $\lambda$  = 546,07 nm

No specific tolerance for the power deviation, irregularity or rotationally invariant irregularity is given; however, the total rms difference between the actual wavefront and the theoretical planar wavefront shall be less than 0,07 waves in single-pass wavefront deformation, and the rms rotationally varying wavefront deviation in single-pass wavefront deformation shall be less than 0,04 waves. The wavelength for all wavefront deformation specifications is  $\lambda = 546,07$  nm.

EXAMPLE 8 13/— PV (0,5  $\mu$ m);  $\lambda$  = 546,07 nm

A specification for a peak-to-valley wavefront deviation which takes the radius tolerance into account. The wavelength for all wavefront deformation specifications is  $\lambda$  = 546,07 nm.

EXAMPLE 9 13/1 (–) RMSi < 10 nm; PVr (50 nm) ;  $\lambda$  = 546,07 nm

A specification for a robust peak-to-valley wavefront deviation without a radius tolerance is given. In addition, a power deviation and the rms of the irregularity is specified as well. The power deviation does influence the RMSi but not the PVr. The wavelength for all wavefront deformation specifications is  $\lambda = 546,07$  nm.

EXAMPLE 10 13/2; 0 (1/–) RMSi < 0,2; Z(N = 4) (RMS < 0,4); Z(6,0)(PV < 0,2);  $\lambda = 546,07$  nm

An off-axis (along X) segment of an aspheric surface is toleranced. Beside a power deviation in X, a peak-to-valley and rms tolerance for the irregularity is used. In addition, the rms deviation of Zernike polynomial fit for the set N = 4 and the peak-to-valley tolerance for Z(6,0) are defined.

EXAMPLE 11 13/2  $\mu$ m (1  $\mu$ m/–) RMSi < 0,2  $\mu$ m; Z(4,0) (PV < 0,5);  $\lambda$  = 546,07 nm

A specification for an aspheric surface with power deviation, peak-to-valley and rms of the irregularity and a peak-to-valley deviation specification of Z(4,0) is given.

EXAMPLE 12  $13/(-(0,1)); \lambda = 632,8 \text{ nm}$ 

Target w(r,  $\theta$ ) = 1,24 Z(4,0) – 0,44 Z(6,0)

No specific tolerance is given for the power deviation and the rotationally invariant irregularity. The nominal theoretical wavefront consists of the reference sphere or plane plus the following polynomial:

Target w(r,  $\theta$ ) = 1,24 Z(4,0) - 0,44 Z(6,0) = 1,24 (6 r<sup>4</sup> - 6 r<sup>2</sup> + 1) - 0,44 (20 r<sup>6</sup> - 30 r<sup>4</sup> + 12 r<sup>2</sup> - 1)

The tolerance for the irregularity (compared to this aspheric wavefront) is 0,1 wavelengths of single-pass wavefront deformation. The wavelength for all wavefront deformation specifications (including the target aberrations) is  $\lambda = 632,8$  nm.

# **Bibliography**

- [1] ISO/TR 14999-1:2005, Optics and photonics Interferometric measurement of optical elements and optical systems Part 1: Terms, definitions and fundamental relationships
- [2] ISO/TR 14999-2:2005, Optics and photonics Interferometric measurement of optical elements and optical systems Part 2: Measurement and evaluation techniques

#### (Continued from second cover)

The Committee has reviewed the provisions of the following International Standard referred in this adopted standard and has decided that it is acceptable for use in conjunction with this standard.

International Standard

Title

ISO 14999-4 Optics and photonics — Interferometric measurement of optical elements and optical systems — Part 4: Interpretation and evaluation of tolerances specified in ISO 10110

For the purpose of deciding whether a particular requirement of this standard is complied with, the final value, observed or calculated expressing the result of a test or analysis, shall be rounded off in accordance with IS 2 : 2022 'Rules for rounding off numerical values (*second revision*)'. The number of significant places retained in the rounded off value should be the same as that of the specified value in this standard.

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This Indian Standard has been developed from Doc No.: PGD 39 (23510).

#### **Amendments Issued Since Publication**

Amend No.	Date of Issue	Text Affected	

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